

Title (en)

SPUTTERING SURFACE TREATMENT FOR ACTIVE FILTER

Title (de)

SPUTTER-OBERFLÄCHENBEHANDLUNG FÜR AKTIVE FILTER

Title (fr)

TRAITEMENT SURFACIQUE PAR PULVÉRISATION CATHODIQUE POUR FILTRE ACTIF

Publication

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Application

EP 20848804 A 20201217

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- FR 2020052502 W 20201217

Abstract (en)

[origin: WO2021123640A1] The invention relates to a method of surface treatment in order to constitute an active filter (21) for a reactive compound of a gas mixture, the method comprising a step of depositing at least one layer of an absorbing material on the surface of a support, the deposition step being carried out by sputtering of an electrode (7) comprising at least one absorbing material chosen to react with the reactive compound of the gas mixture.

IPC 8 full level

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CPC (source: EP)

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Citation (search report)

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